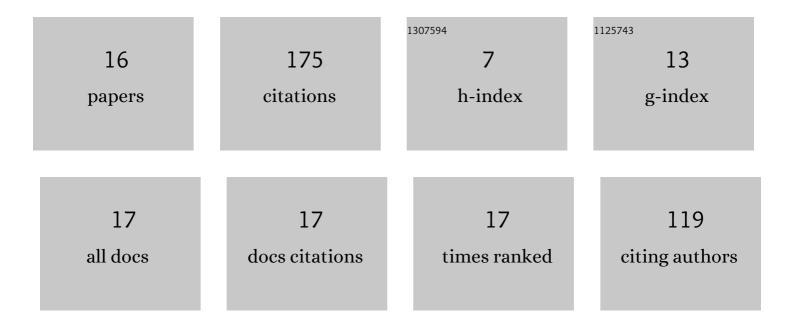
## Hyug-Gyo Rhee

List of Publications by Year in descending order

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HVUC-CVO RHEE

#	Article	IF	CITATIONS
1	Dual-path Phase Unwrapping Algorithm Based on Geodesic Curvature for Interferometric Fringe Analysis. Journal of the Korean Physical Society, 2020, 76, 202-209.	0.7	1
2	Single-shot deflectometry for dynamic 3D surface profile measurement by modified spatial-carrier frequency phase-shifting method. Scientific Reports, 2019, 9, 3157.	3.3	24
3	Fabrication of Dual-Line by Using a Laser Ablation Phenomenon in Direct Laser Lithographic System. Journal of the Korean Society for Precision Engineering, 2019, 36, 1003-1007.	0.2	0
4	Improved wavefront reconstruction algorithm from slope measurements. Journal of the Korean Physical Society, 2017, 70, 469-474.	0.7	9
5	Simultaneous measurements of top surface and its underlying film surfaces in multilayer film structure. Scientific Reports, 2017, 7, 11843.	3.3	19
6	Denoising phase unwrapping algorithm for precise phase shifting interferometry. Journal of the Korean Physical Society, 2017, 71, 82-87.	0.7	2
7	Dual-line fabrication method in direct laser lithography to reduce the manufacturing time of diffractive optics elements. Optics Express, 2017, 25, 1636.	3.4	7
8	Modeling of edge tool influence functions for computer controlled optical surfacing process. International Journal of Advanced Manufacturing Technology, 2016, 83, 911-917.	3.0	11
9	Pixel-based absolute test of a 1-m lightweight mirror for a space telescope. Journal of the Korean Physical Society, 2014, 65, 1385-1389.	0.7	7
10	Enhancement of height resolution in direct laser lithography. Optics Express, 2012, 20, 291.	3.4	3
11	Stress-relieved assembly method for a high-resolution airborne optical system. Journal of the Korean Physical Society, 2012, 60, 1032-1036.	0.7	2
12	Performance evaluation of laser lithographic machine for computer-generated hologram. International Journal of Advanced Manufacturing Technology, 2011, 52, 1005-1009.	3.0	3
13	Improvement of linewidth in laser beam lithographed computer generated hologram. Optics Express, 2010, 18, 1734.	3.4	19
14	Realization and performance evaluation of high speed autofocusing for direct laser lithography. Review of Scientific Instruments, 2009, 80, 073103.	1.3	42
15	300 mm reference wafer fabrication by using direct laser lithography. Review of Scientific Instruments, 2008, 79, 103103.	1.3	8
16	Absolute three-dimensional coordinate measurement by the two-point diffraction interferometry. Optics Express, 2007, 15, 4435.	3.4	18